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Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
		(250/372.ccls. 250/373.ccls. 356/237.4.ccls. 356/237.5.ccls.) and @pd<"20021017" and optical and inspection and system and (photomask and reticle and wafer)	USPAT	OR	OFF	2005/08/22 10:22
		(flow adj system) ((optical adj surface) or (optical component)) impurities	US-PGPUB; USPAT	AND	OFF	2005/08/16 13:01
		(flow adj system) near ((optical adj components) or (optical adj surface)) uv contaminants	US-PGPUB; USPAT	AND	OFF	2005/08/16 12:59
		(flow adj system) near ((optical adj surface) or (optical adj components))	USPAT	AND	OFF	2005/08/16 12:57
		(250/372.ccls. 250/373.ccls. 356/237.4.ccls. 356/237.5.ccls.) and optical and (inspection adj system) and uv and	USPAT	OR	OFF	2005/08/22 10:17
		(250/372.ccls. 250/373.ccls. 356/237.4.ccls. 356/237.5.ccls.) and optical and flaws and uv and impurities	USPAT	OR	OFF	2005/08/22 10:20
S1	7	(250/372.ccls. 250/373.ccls. 356/237.4.ccls. 356/237.5.ccls.) and optical and flaws and gas	USPAT	OR	OFF	2005/08/22 09:54
S2	1	(250/372.ccls. 250/373.ccls. 356/237.4.ccls. 356/237.5.ccls.) and @pd<"20021017" and optical and flaws and gas	USPAT	OR	OFF	2005/08/12 15:00
S3	176	(250/372.ccls. 250/373.ccls. 356/237.4.ccls. 356/237.5.ccls.) and @pd<"20021017" and optical and inspection and system and (photomask reticle wafer)	USPAT	OR	OFF	2005/08/17 10:21
S4	199	(250/372.ccls. 250/373.ccls. 356/237.4.ccls. 356/237.5.ccls.) and optical and (inspection adj system)	USPAT	OR	OFF	2005/08/15 10:20
S5	30	(250/372.ccls. 250/373.ccls. 356/237.4.ccls. 356/237.5.ccls.) and optical and (inspection adj system) and uv	USPAT	OR	OFF	2005/08/15 10:21
S6	25	(250/372.ccls. 250/373.ccls. 356/237.4.ccls. 356/237.5.ccls.) and optical and (inspection adj system) and uv and @ad<"20021017"	USPAT	OR	OFF	2005/08/15 10:30



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S7		(250/372.ccls. 250/373.ccls. 356/237.4.ccls. 356/237.5.ccls.) and optical and (inspection adj system) and uv and @ad<"20021017" not semiconductor	USPAT	OR	OFF	2005/08/15 10:30
S8	30	(250/372.ccls. 250/373.ccls. 356/237.4.ccls. 356/237.5.ccls.) and optical and (inspection adj system) and uv	USPAT	OR	OFF	2005/08/15 15:48
S9	3	(250/372.ccls. 250/373.ccls. 356/237.4.ccls. 356/237.5.ccls.) and (gas adj purge)	USPAT	OR	OFF	2005/08/15 15:50
S10	3	(250/372.ccls. 250/373.ccls. 356/237.4.ccls. 356/237.5.ccls.) and gas and purge and impurities	USPAT	OR	OFF	2005/08/15 15:52
S11	0	clean out impurities with a gas purge	USPAT	ADJ	OFF	2005/08/15 15:52
S12	4628	remove impurities gas purge	USPAT	AND	OFF	2005/08/15 15:52
S13	816	remove impurities gas purge optical	USPAT	AND	OFF	2005/08/15 15:55
S14	0	remove impurities gas purge optical transports adj contaminants	USPAT	AND	OFF	2005/08/15 15:53
S15	0	remove impurities gas purge optical (transports adj contaminants)	USPAT	AND	OFF	2005/08/15 15:53
S16	8	remove impurities gas purge (optical adj surface)	USPAT	AND	OFF	2005/08/15 15:56
S17	3	remove impurities (gas adj stream) (optical adj surface)	USPAT	AND	OFF	2005/08/15 15:58
S18	8	remove impurities (gas adj stream) (optical adj surface)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	OFF	2005/08/15 15:59
S19		(gas adj purge adj system adj removes) impurities optical	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	OFF	2005/08/15 16:00
S20		(gas adj purge adj system adj removes)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	OFF	2005/08/15 16:00

S21	250	(gas adj purge adj system)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	OFF	2005/08/15 16:01
S22	0	(gas adj purge adj system) (blocks adj contaminants)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	OFF	2005/08/15 16:13
S23	0	transparent adj cover adj blocks adjoptical adj component	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	OFF	2005/08/15 16:14
S24		transparent adj cover adj blocks adj optical adj component	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	OFF	2005/08/15 16:14
S25	48	transparent adj cover optical adj component	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	OFF	2005/08/15 16:15
S26	13	(transparent adj cover) (optical adj component) uv	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	OFF	2005/08/15 16:21
S27	0	(transparent adj cover adj protects) (optical adj component) uv	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	OFF	2005/08/15 16:21
S28	0	(transparent adj screen adj protects) (optical adj component) uv	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	OFF	2005/08/15 16:22



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S29	42	transparent cover protects (optical adj component) uv	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	OFF	2005/08/15 16:22
S30	0	transparent near cover near protects near (optical adj component)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	OFF	2005/08/15 16:26
S31	0	cover near protects near (optical adj component)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	OFF	2005/08/15 16:26
S32	473	optical device transparent adj over	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	OFF	2005/08/15 16:26
S33	168	(optical adj device) (transparent adj cover)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	OFF	2005/08/15 16:27
S34	2	(optical adj device) near (transparent adj cover)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	OFF	2005/08/15 16:27
S35	7	(inert adj gas) (contaminant\$1 adj remov\$3) (optic\$2 adj component\$1) (gas adj stream\$2)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	OFF	2005/08/16 10:23
S36	29	(optic\$2 component\$1) near cover	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	OFF	2005/08/16 10:25



S37	23	(optic\$2 component\$1) near cover not golf	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	OFF	2005/08/16 10:25
S38	16	(optic\$2 component\$1) near cover not golf @pd<"20021017"	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	OFF	2005/08/16 10:29
S39	45774	(optic\$2 component\$1) shield\$2 or (physically adj block) @pd<"20021017"	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	OFF	2005/08/16 10:30
S40	9	(optic\$2 component\$1) shield\$2 (physically adj block) @pd<"20021017"	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	OFF	2005/08/16 10:31
S41	10715	(optic\$2 component\$1) shield\$2 transparent @pd<"20021017"	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND .	OFF	2005/08/16 10:31
S42	1	(optic\$2 component\$1) (contaminant adj shield\$2) transparent @pd<"20021017"	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	OFF	2005/08/16 10:36
S43	38	(optic\$2 component\$1) (lens adj shield\$2) transparent @pd<"20021017"	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	OFF	2005/08/16 10:38
S44	. 1	(optic\$2 component\$1) (lens adj shield\$2) transparent @pd<"20021017" contaminant	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	OFF .	2005/08/16 10:38



S45	2	(optic\$2 component\$1) (lens adj shield\$2) transparent @pd<"20021017" impurit\$3	US-PGPUB; USPAT; USOCR;	AND	OFF	2005/08/16 10:46
			EPO; JPO; DERWENT; IBM_TDB		•	
S46	36228	optical (housing or shield) transparent @pd<"20021017"	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	OFF	2005/08/16 10:47
S47	357	(optical adj (housing or shield)) transparent @pd<"20021017"	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	OFF	2005/08/16 10;47
S48	30	(optical adj (housing or shield)) transparent @pd<"20021017" uv	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	OFF	2005/08/16 10:49
S49	21	(optical adj (housing or shield)) transparent @pd<"20021017" uv not blood not tissue	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	OFF	2005/08/16 10:49
S50	269	(flow adj system) ((optical adj surface) or (optical component)) impurities	US-PGPUB; USPAT	AND	OFF	2005/08/16 13:02
S51	14	(flow adj system) ((optical adj surface) or (optical component)) (remove adj contaminants)	US-PGPUB; USPAT	AND	OFF	2005/08/16 13:04
S52	749	(flow adj system) ((optical adj surface) or (optical component)) clean\$3	US-PGPUB; USPAT	AND	OFF	2005/08/16 13:05
S53	0	(flow adj system) ((optical adj surface) or (optical component)) near clean\$3	US-PGPUB; USPAT	AND	OFF	2005/08/16 13:05
S54	0	(flow adj system) near clean\$3 near ((optical adj surface) or (optical component))	US-PGPUB; USPAT	AND	OFF	2005/08/16 13:06
S55	4496	cleaning optical components gas stream	US-PGPUB; USPAT	AND	OFF	2005/08/16 13:06
S56	787	cleaning optical components gas stream inspection system	US-PGPUB; USPAT	AND	OFF	2005/08/16 13:06
These Exami	searches we ners Autom	releaning optical components gasbase area Search 1881 (EAST) V2.0.1		AND PTO Copyi	OFF ight 199	2005/08/16 13:06



S58	260	cleaning optical components gas adj stream inspection system	US-PGPUB; USPAT	AND	OFF	2005/08/16 13:17
S59	1	("5531857").PN.	USPAT; USOCR	OR	OFF	2005/08/16 13:17
S60	1	"5531857".pn. uv	US-PGPUB; USPAT	AND	OFF	2005/08/16 13:17
S61	1	("5216479").PN.	USPAT; USOCR	OR	OFF	2005/08/17 09:10
S62	33	(250/372.ccls. 250/373.ccls. 356/237.4.ccls. 356/237.5.ccls.) and @pd<"20021017" and optical and inspection and system and photomask and reticle and wafer	US-PGPUB; USPAT	OR	OFF	2005/08/17 10:23
S63	31	(250/372.ccls. 250/373.ccls. 356/237.4.ccls. 356/237.5.ccls.) and @pd<"20021017" and optical and inspection and system and photomask and reticle and wafer and semiconductor	US-PGPUB; USPAT	OR	OFF	2005/08/17 10:23
S64	18	(250/372.ccls. 250/373.ccls. 356/237.4.ccls. 356/237.5.ccls.) and @pd<"20021017" and optical and inspection and system and photomask and reticle and wafer and semiconductor and manufacturing	US-PGPUB; USPAT	OR	OFF	2005/08/17 11:00
S65		(250/372.ccls. 250/373.ccls. 356/237.4.ccls. 356/237.5.ccls.) and @pd<"20021017" and optical and inspection and system and photomask and reticle and wafer and semiconductor and manufacturing and (optic adj membrane)	US-PGPUB; USPAT	OR	OFF	2005/08/17 11:01
S66	0	(250/372.ccls. 250/373.ccls. 356/237.4.ccls. 356/237.5.ccls.) and @pd<"20021017" and optical and inspection and system and (optic adj membrane)	US-PGPUB; USPAT	OR	OFF	2005/08/17 11:01
S67	0	(250/372.ccls. 250/373.ccls. 356/237.4.ccls. 356/237.5.ccls.) and @pd<"20021017" and optical and inspection and system and (optic\$2 adj membrane)	US-PGPUB; USPAT	OR	OFF	2005/08/17 11:01
S68	4	@pd<"20021017" and optical and inspection and system and (optic\$2 adj membrane)	US-PGPUB; USPAT	OR	OFF	2005/08/17 11:05
S69	1	·@pd<"20021017" (optic\$2 adj membrane) transparent cover contaminant\$3	US-PGPUB; USPAT	AND	OFF	2005/08/17 11:06
These	searches we	re performed in the following database	<u>.</u>	l	1	De 6

Examiners Automated Search Tool (EAST) V2.0.1



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S70	2997	optical inspection system (lens same (cover or protection or shield))	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	ON	2005/08/19 11:34
S71	57	optical inspection system (lens same (cover or protection or shield)) uv detector analyzer	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	ON	2005/08/19 11:39
S72	33	optical inspection system (lens same (cover or protection or shield)) uv detector analyzer @ad<"20021017"	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	ON	2005/08/19 11:42
S73	20	optical inspection system (lens same (cover or protection or shield)) uv detector analyzer @pd<"20021017"	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	ON	2005/08/19 11:46
S74	10	optical inspection system (lens same (cover or protector or shield)) uv detector analyzer @pd<"20021017"	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	ON	2005/08/19 11:51
S75	1795	(lens same (cover or protector or shield)) uv @pd<"20021017"	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	ON	2005/08/19 11:52
S76	170	(lens same (cover or protector or shield)) contaminants uv @pd<"20021017"	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	ON	2005/08/19 11:53
S77	0	(250/372.ccls. 250/373.ccls. 356/237.4.ccls. 356/237.5.ccls.) (exposed adj optical adj surface)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	ON	2005/08/19 14:53



S78	57	(exposed adj optical adj surface)	US-PGPUB;	AND	ON	2005/08/19 16:25
			USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB			,
S79	13	(exposed adj optical adj surface) frame	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	ON	2005/08/19 14:54
S80	2	("6,031,598").PN.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/08/19 14:55
S81	2	("5275553").PN.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/08/19 16:25
S82	1159	250/372.ccls.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/08/22 09:17
S83	450	250/373.ccls.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/08/22 09:54
S84	278	356/237.4.ccls.	USPAT	OR	OFF	2005/08/22 10:20
S85	0	356/237.ccls.	USPAT	OR	OFF	2005/08/22 10:20
S86	444	356/237.5.ccls.	USPAT	OR	OFF	2005/08/22 10:21
S87	575	(356/237.4.ccls. 356/237.5.ccls.) and @ad<"20021017"	USPAT	OR	OFF	2005/08/22 10:23
S88	640	(356/237.4.ccls. 356/237.5.ccls.) and @ad<"20021017"	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/08/22 10:59



S89		(356/237.4.ccls. 356/237.5.ccls.) and @ad<"20021017" and (transparent adj cover)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/08/22 11:00
S90	229	(356/237.4.ccls. 356/237.5.ccls.) and @ad<"20021017" and transparent	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/08/22 11:02
S91	198	(356/237.4.ccls. 356/237.5.ccls.) and @ad<"20021017" and transparent and inspection	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/08/22 11:02
S92	9	(356/237.4.ccls. 356/237.5.ccls.) and @ad<"20021017" and transparent and inspection and (semi near conductor)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/08/22 11:09
S93	160	(356/237.4.ccls. 356/237.5.ccls.) and @ad<"20021017" and transparent and inspection and (semiconductor)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/08/22 11:09
S94	0	("na9206139").PN.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/08/22 11:50
S95	0	dust entrapment design for optical path	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	ON	2005/08/22 11:51
S96	633	dust entrapment design	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND .	ON	2005/08/22 11:51



S97	. 147	dust entrapment design optical	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	ON	2005/08/22 11:51
S98	68	dust entrapment design optical path	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	ON	2005/08/22 11:51
S99	30449	hydrocarbons inorganics moisture	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	ON.	2005/08/22 14:26
S10 0	6	(("6201250") or ("5812314") or ("6201209")).PN. or ((2003/0132210a1) or (2002/0000519a1) or (2003/0142403a1)).CCLS.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/08/24 10:10